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PATENT

Atty. Docket No.: 006915 USA P02/IMPLANT/P3I/AG

MAR 1 2 2007

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

e Application of:

Kenneth Collins, et al.

:

Entitled: PLASMA IMMERSION ION

IMPLANTATION APPARATUS USING A

PLASMA SOURCE HAVING LOW

DISSOCIATION AND LOW MINIMUM

PLASMA VOLTAGE

: Examiner: Jack S. Chen

: Group Art Unit: 2813

Serial No.: 10/646,533

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Filing Date: August 22, 2003

AMENDMENT UNDER 37 CFR. 1.111 (RESPONSE TO DOUBLE PATENTING REJECTION)

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

In response to the Office Action dated February 9, 2007, please amend the above-identified application as follows:

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks/Arguments begin on page 18 of this paper.